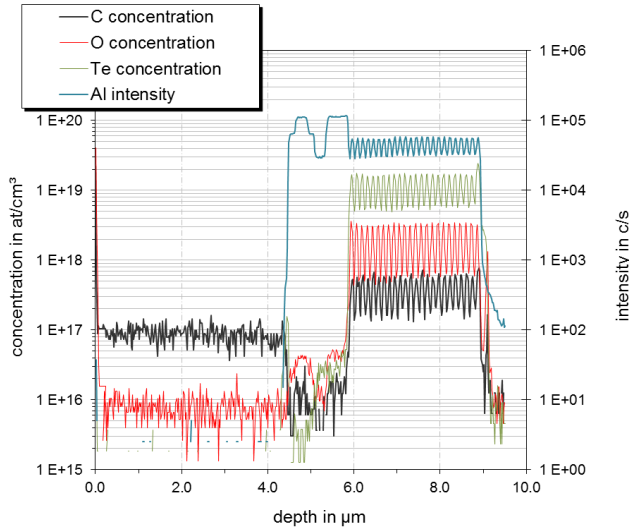
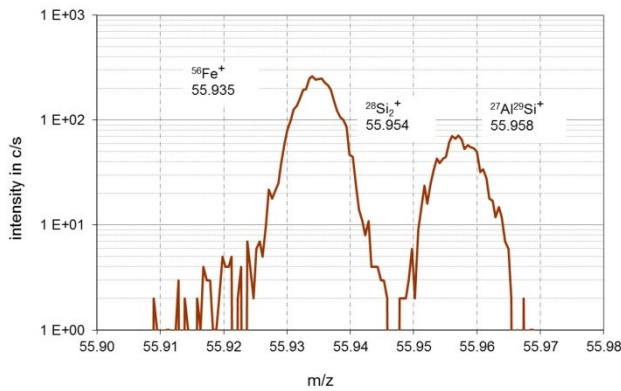


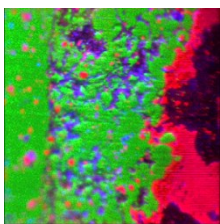
SIMS Analytics of Dopants, Impurities and Matrix Compositions



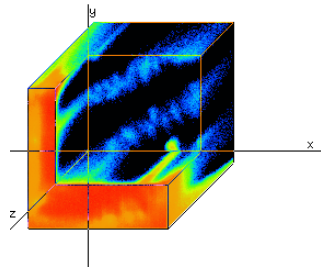
Depth profile of a phosphide-arsenide layer system of a LED



High resolved mass spectrum



Lateral element distribution of a biological Titanium implant (Ti - green, Na - blue, Ca - red)



Three dimensional distribution of oxygen in silicon

Main Applications

- Quantification of dopants and impurities
 - Access to a huge pool of calibration standards
- Determination of matrix composition
- Depth profiling
- Mapping of lateral element distribution
- Three dimensional analyses of microvolumes
- Mass spectra
- Failure analyses

Materials (Selection)

- III/V Semiconductors (GaAs, GaN, GaP, InP, ternary, quaternary)
- Silicon, germanium, silicides
- II/VI semiconductors (CdTe, ZnO, ZnSe)
- Optical multilayers
- Metal layer structures, contact systems
- Solar cells (Si, CIGS, CIGSe)
- Metal ceramic and ceramic compound systems
- Polymers
- Medical and biological samples (implants, dental materials)

Strengths of SIMS

- High detection sensitivities (ppm and better)
- Depth profiles with high depth resolution (5 nm) and low detection limits
- Detection of all elements from H to U
- High lateral resolution (1µm)
- High signal dynamics (6 orders of magnitude)

Limitations of SIMS

- Destruction of the sample surface
- Mixing and recoil processes
- Topographical effects, surface roughness
- High variation of ionisation cross sections
- Matrix dependence of detection sensitivities
- No information about chemical bonds
- Solid and vacuum resistant samples are required